

FIG. 1

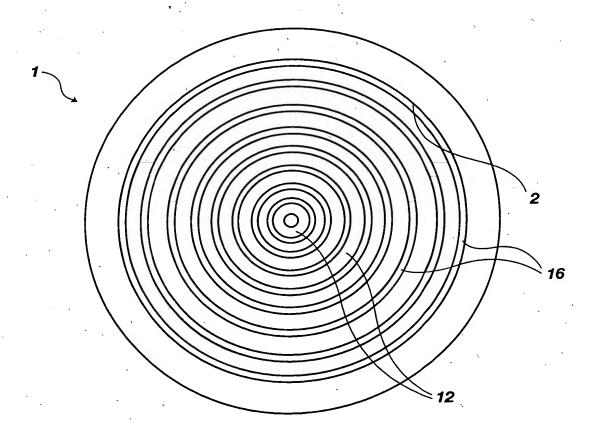


FIG. 2

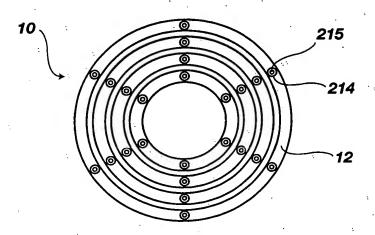


FIG. 1A

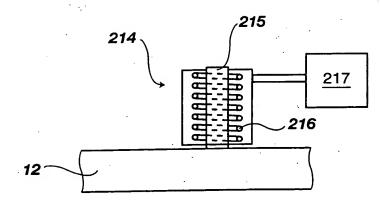


FIG. 1B

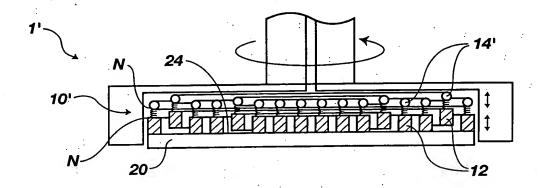


FIG. 3

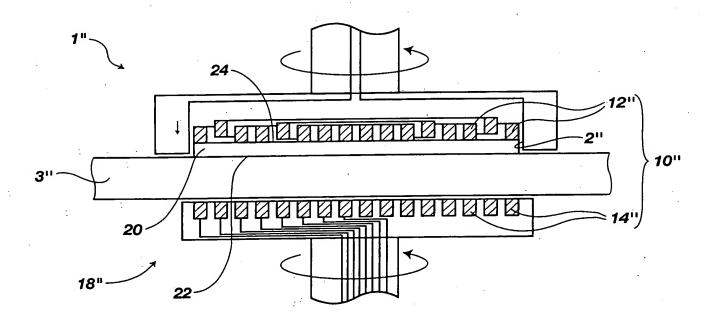


FIG. 4

TITLE: POLISHING SYSTEMS FOR USE WITH SEMICONDUCTOR SUBSTRATES INCLUDING DIFFERENTIAL PRESSURE APPLICATION APPARATUS Inventor: Nathan R. Brown Docket No.: 2269-4375.1US

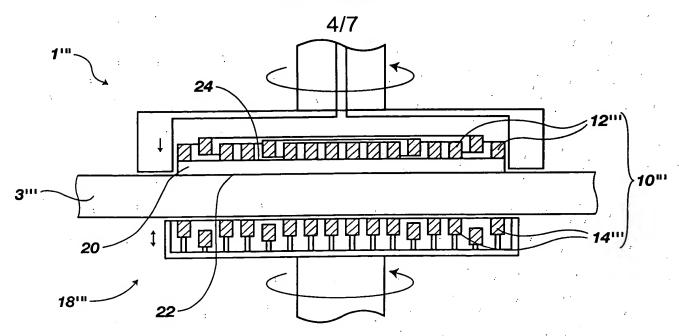


FIG. 5

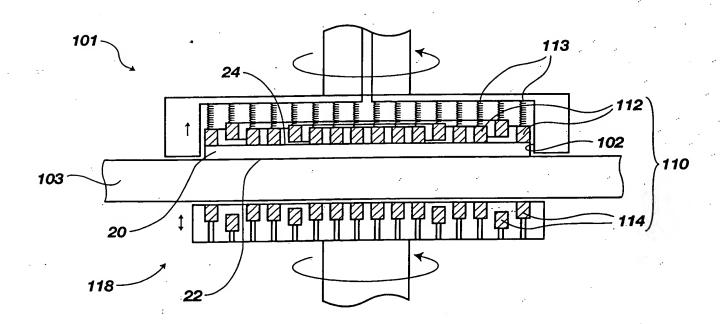
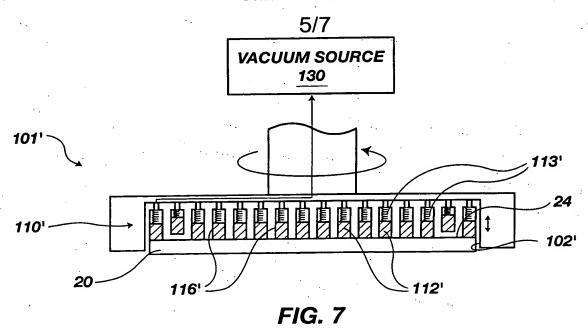
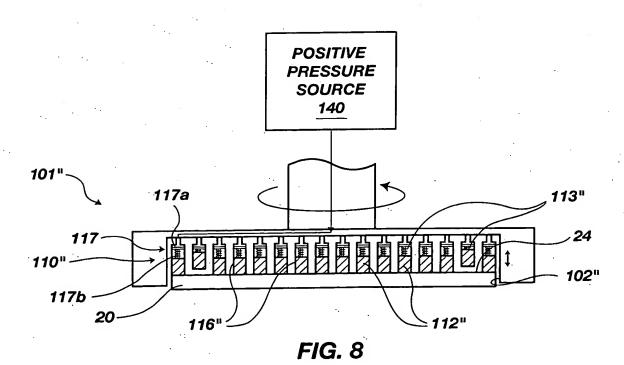
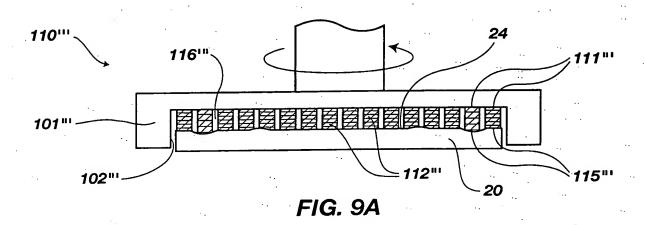


FIG. 6

TITLE: POLISHING SYSTEMS FOR USE WITH SEMICONDUCTOR SUBSTRATES INCLUDING DIFFERENTIAL PRESSURE APPLICATION APPARATUS Inventor: Nathan R. Brown Docket No.: 2269-4375.1US







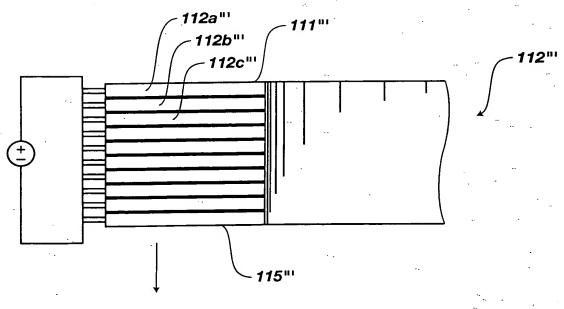


FIG. 9B

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